

In the Specification:

On page 1 lines 1 and 2, please amend the Title of the Invention as follows:

**TRAILING EDGE TAPER DESIGN AND METHOD FOR
MAKING A PERPENDICULAR WRITE HEAD WITH SHIELDING**

On page 19 lines 1 and 2, please amend the Title of the Invention as follows:

**TRAILING EDGE TAPER DESIGN AND METHOD FOR
MAKING A PERPENDICULAR WRITE HEAD WITH SHIELDING**

On page 19, please amend the Abstract as follows:

A magnetic write head for ~~as use~~ in perpendicular magnetic data recording. The write head includes a write pole and a trailing shield having a tapered surface. A return pole stitched to the trailing shield is magnetically connected with the write pole at a location away from the air bearing surface (ABS).

Please amend the paragraph beginning on page 10, line 20 as follows:

With reference now to Fig. 6, a REI RIE process may be performed to remove portions of the Ta layer **510** and **508**. Preferably the REI RIE process is performed at an angle as shown, so that the shadowing effect of the mask will promote a tapered removal of material also as shown. Since as mentioned above, the first magnetic pole

layer **506** is constructed of a material that is not as readily removed by RIE, the surface will tend flatten out when that surface is reached and at that point the RIE process should be stopped.